

## Patent Abstracts of Japan

PUBLICATION NUMBER : 63271147  
PUBLICATION DATE : 09-11-88

APPLICATION DATE : 28-04-87  
APPLICATION NUMBER : 62105949

APPLICANT : SHIMADZU CORP;

INVENTOR : OKASHITA HIDEO;

INT.CL. : G01N 23/223

TITLE : ANALYSIS BY FUNDAMENTAL PARAMETER METHOD

ABSTRACT : PURPOSE: To exactly calculate background intensity by using a sample for background calculation without contg. analysis components in addition to a standard sample.

CONSTITUTION: The sample for background calculation is particularly prepd. in addition to the general standard sample and the background intensity is calculated from said sample in a fundamental parameter method. The sample which has the purity as high as, for example,  $\geq 99\%$  and is harmless, free from deterioration in properties, simple in compsn. and inexpensive is preferable as the sample for background calculation.  $\text{Li}_2\text{B}_4\text{O}_7$  is used for the powder sample of such sample and  $\text{CaCO}_3$  without contg. boron is used in the case of analyzing boron. Fe is used for the metallic sample and metals such as Al, Ni and Cu are used for analysis of Fe. The sample for such background calculation may be used alone or used in combination of  $\geq 2$  kinds.

COPYRIGHT: (C)1988,JPO&Japio